



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Satoshi TATSUURA et al.

Group Art Unit: 1753

Application No.: 10/082,228

Examiner: E. Wong

Filed: February 26, 2002

Docket No.: 106200.01

For: METHOD FOR ELECTRODEPOSITED FILM FORMATION, METHOD FOR
ELECTRODE FORMATION, AND APPARATUS FOR ELECTRODEPOSITED FILM
FORMATION

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

After entry of the Amendment After Final Rejection filed October 13, 2004, please
consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.